

| L Number | Hits   | Search Text  | DB  | Time stamp          |
|----------|--------|--|---|---------------------|
| -        | 2      | ("6122042").PN.  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 15:47    |
| -        | 2      | ("20020003169").PN.  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 19:03    |
| -        | 2      | ("6222208").PN.  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 15:58 .. |
| -        | 489    | (257/254,471).CCLS.  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 15:58    |
| -        | 19     | display and ((257/254,471).CCLS.)  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 17:22    |
| -        | 107919 | (micromechanical or strain or pressure or piezoelectric) near1 (sensor or sensors)   | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 16:47    |
| -        | 1117   | (pixels or pixel) and ((micromechanical or strain or pressure or piezoelectric) near1 (sensor or sensors))   | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 16:47    |
| -        | 3018   | pitch and ((micromechanical or strain or pressure or piezoelectric) near1 (sensor or sensors))   | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 16:49    |
| -        | 20505  | ((light adj1 emitting) or led or display) and ((micromechanical or strain or pressure or piezoelectric) near1 (sensor or sensors))   | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 16:48    |
| -        | 1371   | pitch and (((light adj1 emitting) or led or display) and ((micromechanical or strain or pressure or piezoelectric) near1 (sensor or sensors)))                                       | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 16:49 .. |
| -        | 380    | substrate and (pitch and ((light adj1 emitting) or led or display) and ((micromechanical or strain or pressure or piezoelectric) near1 (sensor or sensors))))                        | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 16:55    |
| -        | 0      | (substrate near2 semiconductor) and (pitch and (((light adj1 emitting) or led or display) and ((micromechanical or strain or pressure or piezoelectric) near1 (sensor or sensors)))) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 16:56 .. |
| -        | 70     | (substrate near2 semiconductor) and (pitch and (((light adj1 emitting) or led or display) and ((micromechanical or strain or pressure or piezoelectric) near1 (sensor or sensors)))) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29 17:16    |

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|---|--------|--|---|---------------------|
| - | 1163   | (integrate or integrated or intergarting) with display with sensor   | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>17:17 |
| - | 30     | (integrate or integrated or intergarting) with display with sensor with logic  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>17:21 |
| - | 467490 | ((wafer or substrate) with semiconductor)  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>17:21 |
| - | 1483   | display same ("pn" or "p-n")   | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>17:25 |
| - | 4      | (display same ("pn" or "p-n") ) same ((micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors))  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>17:25 |
| - | 80185  | display same (pixel or pixels)   | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>17:40 |
| - | 21     | (display same (pixel or pixels) ) same ((micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors))  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>17:41 |
| - | 12310  | display same (pitch)   | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>17:41 |
| - | 24     | (display same (pitch) ) same ((micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors))  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>17:51 |
| - | 443238 | (strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>18:51 |
| - | 7978   | ((gallium adj1 arsenide) or gaas) same (display or led or (light adj1 (emitter or emitting)))  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>18:49 |
| - | 384    | ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and ((gallium adj1 arsenide) or gaas) same (display or led or (light adj1 (emitter or emitting)))) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>18:51 |
| - | 469803 | (substrate or wafer) with (semiconductor or semiconductive)  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB | 2004/02/29<br>17:56 |

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| - | 104   | ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adj1 arsenide) or gaas) same (display or led or (light adj1 (emitter or emitting)))) and ((substrate or wafer) with (semiconductor or semiconductive)) | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/02/29 18:50 .. |
| - | 61675 | display and ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)).  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/02/29 18:51 .. |
| - | 13966 | ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((wafer or substrate) with semiconductor))   | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/02/29 18:51 .. |
| - | 2574  | display and (((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((wafer or substrate) with semiconductor)))   | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/02/29 18:51 .. |
| - | 20961 | ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) same display  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/02/29 18:51 .. |
| - | 487   | (((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) same display) and (((wafer or substrate) with semiconductor))  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/03/01 14:00 .. |
| - | 2     | ("5324980").PN.   | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/03/01 15:57 .. |
| - | 15    | 5324980.URPN.   | USPAT                                       | 2004/03/01 14:00 .. |
| - | 0     | ("strainwithpressurewithsensor").PN.  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/03/01 15:58 .. |
| - | 3304  | strain with pressure with sensor  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/03/01 15:58 .. |
| - | 149   | (strain with pressure with sensor) and semiconductor adj substrate  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/03/01 16:14 .. |
| - | 6     | display same pitch same gaas  | USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB | 2004/03/01 16:14 .. |